



Docket No. 01SC062US2

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: James Chingwei Li

Serial No. 10/675,680

Examiner: Victor V. Yevsikov

Filed: September 29, 2003

Art Unit: 2825

Title: TESTING APPARATUS AND METHOD FOR DETERMINING AN ETCH  
BIAS ASSOCIATED WITH A SEMICONDUCTOR-PROCESSING STEP

Commissioner for Patents  
Mail Stop Issue Fee  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

COMMENTS ON STATEMENT OF REASONS FOR ALLOWANCE

Sir:

Applicant agrees that the Examiner has accurately stated one reason for allowance of the claims. However, the claims include other patentable aspects that were not identified by the Examiner. This response is submitted to avoid the possibility of any unnecessary limitation on the scope of the claims which might result from the stated reason for allowance. It is being submitted concurrently with the issue fee payment.

Respectfully submitted,

Richard S. Koppel  
Registration No. 26,475  
Attorney for Applicant

September 28, 2004

KOPPEL, JACOBS, PATRICK & HEYBL  
555 St. Charles Drive, Suite 107  
Thousand Oaks, California  
(805) 373-0060

J\D7\R01SC062 Reasons for Allow